



520.35833VV5

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KAZUMI, et al.  
Serial No.: 10/086,710  
Filed: March 4, 2002  
For: PLASMA PROCESSING APPARATUS  
Group: 1763  
Examiner: Hassanzadeh

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LETTER TO THE OFFICIAL DRAFTSMAN

Commissioner of Patents  
Washington, D.C. 20231

April 14, 2003

Sir:

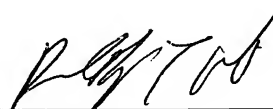
In the above-identified application, Applicants respectfully submit a corrected Drawing Sheet 10 containing an amended Figure 20. The submission is in response to an objection by the Examiner under 37 CFR 1.83(a) that the drawings allegedly fail to show a plate made of a conductor or semiconductor placed on an inner side of the upper face of the vacuum chamber wherein the plate is coupled to an RF, DC or ground. In the corrected drawing sheet, Figure 10 is amended to schematically show the plate coupled to an RF, DC or ground. This feature is described in detail in the specification, for example from page 28, line 21 to page 29, line 3. Accordingly, it is respectfully submitted that no new matter is introduced by the amendment.

It is respectfully submitted that the objection to the drawings is thereby overcome.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By



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